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Advances in Metrology for X-Ray and EUV Optics V

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Haruhiko Ohashi
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Editors

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Contents

v *Authors*
vii *Conference Committee*

SESSION 1 SLOPE PROFILERS

- 9206 02 **A new optical head tracing reflected light for nanoprofiler** [9206-1]
- 9206 03 **The developmental long trace profiler (DLTP) optimized for metrology of side-facing optics at the ALS** [9206-2]
- 9206 04 **Upgrade of surface profiler for x-ray mirror at SPring-8** [9206-4]
- 9206 05 **Ultra-high-precision surface processing techniques for nanofocusing ellipsoidal mirrors in hard x-ray region** [9206-5]
- 9206 06 **Design consideration for nano-accuracy long trace profiler at BSRF** [9206-6]

SESSION 2 AT-WAVELENGTH METROLOGY

- 9206 07 **A reflectometer for at-wavelength characterization of XUV-reflection gratings** [9206-7]
- 9206 08 **At-wavelength metrology of x-ray optics at Diamond Light Source** [9206-8]

SESSION 3 MICROSCOPES/FIGURE INTERFEROMETERS

- 9206 0D **An extreme ultraviolet interferometer suitable to generate dense interference pattern** [9206-13]
- 9206 0E **Experimental results for absolute cylindrical wavefront testing** [9206-14]

SESSION 4 EXTREME ANGLE MEASUREMENTS AND CALIBRATION

- 9206 0F **Pushing the limits: latest developments in angle metrology for the inspection of ultra-precise synchrotron optics (Invited Paper)** [9206-15]
- 9206 0G **Angular calibration of surface slope measuring profilers with a bendable mirror** [9206-16]
- 9206 0H **Design of a precision two-dimensional tip-tilting stage system for autocollimator-based long trace profiler angular calibration** [9206-17]

SESSION 5 FACILITIES

- 9206 0I **A new x-ray optics laboratory (XROL) at the ALS: mission, arrangement, metrology capabilities, performance, and future plans (Invited Paper) [9206-18]**
- 9206 0J **An XUV optics beamline at BESSY II [9206-19]**

Authors

Numbers in the index correspond to the last two digits of the six-digit citation identifier (CID) article numbering system used in Proceedings of SPIE. The first four digits reflect the volume number. Base 36 numbering is employed for the last two digits and indicates the order of articles within the volume. Numbers start with 00, 01, 02, 03, 04, 05, 06, 07, 08, 09, 0A, 0B...0Z, followed by 10-1Z, 20-2Z, etc.

Alatawi, Ayshah, 0E
Alcock, Simon G., 08
Anton, J., 0H
Artemiev, Nikolay A., 03, 0G, 0I
Assoufid, L., 0H
Berujon, Sebastien, 08
Bischoff, P., 07
Chow, Ken P., 0G
Domning, Edward E., 03, 0G
Eggenstein, F., 07, 0J
Endo, K., 02
Erko, A., 0J
Follath, R., 0J
Frolov, O., 0D
Gaupp, A., 07
Geckeler, Ralf D., 0F
Kearney, S., 0H
Kishimoto, H., 04
Kitayama, T., 02
Kolacek, K., 0D
Koyama, Takahisa, 05
Kudo, R., 02
Künstner, S., 0J
Lacey, Ian, 03, 0G, 0I
Li, Ming, 06
Liu, W., 0H
Mast, M., 0J
Matsuyama, Satoshi, 05
McKinney, Wayne R., 03, 0I
Melich, R., 0D
Miura, T., 04
Morrison, Gregory Y., 03
Morton, Simon A., 03
Nakano, M., 02
Ohashi, Haruhiko, 04, 05
Okita, K., 02
Okuda, K., 02
Padmore, Howard A., 0I
Prukner, V., 0D
Qian, J., 0H
Reardon, Patrick J., 0E
Sawhney, Kawal, 08
Schäfers, F., 07, 0J
Schmidt, J. S., 0J
Schmidt, J., 0D
Senba, Y., 04
Senf, F., 07, 0J
Shu, D., 0H
Siewert, Frank, 0F, 0J
Smith, Brian V., 03, 0G
Sokolov, A. A., 07, 0J
Straus, J., 0D
Sullivan, J., 0H
Sutter, John, 08
Tang, Shanzhi, 06
Tokuta, Y., 02
Wang, Hongchang, 08
Wang, Lichao, 06
Wang, Qiushi, 06
Yamamura, K., 02
Yamauchi, Kazuto, 05
Yandayan, Tanfer, 0F
Yang, Fugui, 06
Yashchuk, Valeriy V., 03, 0G, 0I
Yumoto, Hirokatsu, 05
Zeschke, T., 07, 0J

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